

AMENDMENT AND RESPONSE

Serial Number: 08/902,809

Filing Date: July 30, 1997

Title: SELECTIVE SPACER TECHNOLOGY TO PREVENT METAL OXIDE FORMATION DURING POLYCID REOXIDATION

Page 7 of 9

Dkt: 303.278US1

Telephone interview

Applicant thanks Examiner Nadav for the telephone interview granted on Tuesday, September 29, 1998 between himself and Applicant's representatives Mr. Kluth (Reg. No. 32,146) and Mr. Mates (Reg. No. 35,271). In response to the agreement reached in the telephone interview with the Examiner on September 29, 1998, Applicant has amended the specification to include the recitation that the electrode 205 is comprised of polysilicon, a refractory metal, and a dielectric as shown in Figures 2A-2C. Applicant has also added reference numerals 211, 220, and 221 to the specification as shown in Figures 2C and 2D.

Restriction Requirement

Applicant thanks the Examiner for the telephone interview granted on May 22, 1998. Applicant affirms the election of the claims of Group I (claims 13-22) in which the elected group is now represented by new claims 23-43 drawn to a semiconductor device, an electronic device, and a gate electrode. Applicant has canceled non-elected claims 1-12 and elected claims 13-22. Applicant reserves the right to assert non-elected claims 1-12 in a future divisional or continuation application.

Information Disclosure Statement

Applicant respectfully requests that the Information Disclosure Statement filed April 13, 1998, be entered, that the documents listed on the attached Form 1449 be considered by the Examiner and made of record, and that a copy of the Form 1449 with the references initialed be returned to the Applicant.

Applicant is also submitting a Supplemental Information Disclosure Statement with the present Amendment and Response and similarly request that this Supplemental Information Disclosure Statement be entered, that the documents listed on the attached Form 1449 be considered by the Examiner and made of record, and that a copy of the Form 1449 with the references initialed be returned to the Applicant.

R

AMENDMENT AND RESPONSE

Serial Number: 08/902,809

Filing Date: July 30, 1997

Title: SELECTIVE SPACER TECHNOLOGY TO PREVENT METAL OXIDE FORMATION DURING POLYCID REOXIDATION

Page 8 of 9

Dkt: 303.278US1

Objection to the drawings

The drawings were objected to based on the reference characters 211, 220, and 221. As discussed in the telephonic interview on September 29, the reference character 220 indicates a reoxidation of the electrode 205 and the active area 215 shown in Figure 2C, and does not indicate two separate structures. The reference character 221 similarly indicates a reoxidation of the undoped silicon 211 and the active area shown in Figure 2D. The reference characters 211, 220, and 221 have been added to the specification based on our agreement in the interview.

Objection to the disclosure

The disclosure was objected to because of the use of the word "smile" in page 5, line 5. Applicant respectfully submits that the word "smile" is a term known to those skilled in the art. Applicant has attached U.S. Patent Number 5,681,768 to Smayling et al. which discloses an example of the use of the term "smile." This patent is attached for illustrative and teaching purposes only and it need not be submitted in an Information Disclosure Statement under the exception described in MPEP §609 C(3).

The disclosure was objected to based on the abstract. Applicant has submitted a new abstract on a separate page attached hereto.

Rejections Under 35 U.S.C. §112

Claims 13-22 are rejected under 35 U.S.C. § 112. Applicant has canceled the pending claims 13-22 and respectfully submits that the rejection is obviated.

Rejections Under 35 U.S.C. §§ 102 and 103

Claims 13-22 are rejected under 35 U.S.C. §§ 102(b) or 103(a) as being unpatentable over Gonzalez alone or in combination with Watabe et al. Applicant has canceled pending claims 13-22 and respectfully submits that the rejection is obviated.

a

AMENDMENT AND RESPONSE

Serial Number: 08/902,809

Page 9 of 9

Dkt: 303.278US1

Filing Date: July 30, 1997

Title: SELECTIVE SPACER TECHNOLOGY TO PREVENT METAL OXIDE FORMATION DURING POLYCID REOXIDATION

New claims 23-43

Applicant has added new claims 23-43 to more carefully claim the present invention. Each claim includes limitations not disclosed or suggested by Gonzalez or Watabe et al., either alone or in combination. For example, claim 26 recites an electronic device comprising a feature having a surface and a spacer only on the surface of the feature. Neither Gonzalez nor Watabe et al. disclose a spacer only on a surface of a feature.

CONCLUSION

The applicants respectfully submit that the new claims 23-43 are in condition for allowance and request reconsideration of the application and allowance of the claims. The Examiner is invited to telephone the below-signed attorney at 612-373-6973 to discuss any questions which may remain with respect to the present application.

Respectfully submitted,

KLAUS FLORIAN SCHUEGRAF ET AL.

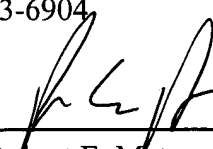
By their Representatives,

SCHWEGMAN, LUNDBERG, WOESSNER & KLUTH, P.A.
P.O. Box 2938
Minneapolis, MN 55402
(612) 373-6904

Date

10/9/98

By


Robert E. Mates
Reg. No. 35,271

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to Assistant Commissioner of Patents, Washington, D.C. 20231 on **October 9, 1998**.

Name

Daniel J. Kluth

Signature

Daniel J. Kluth
